

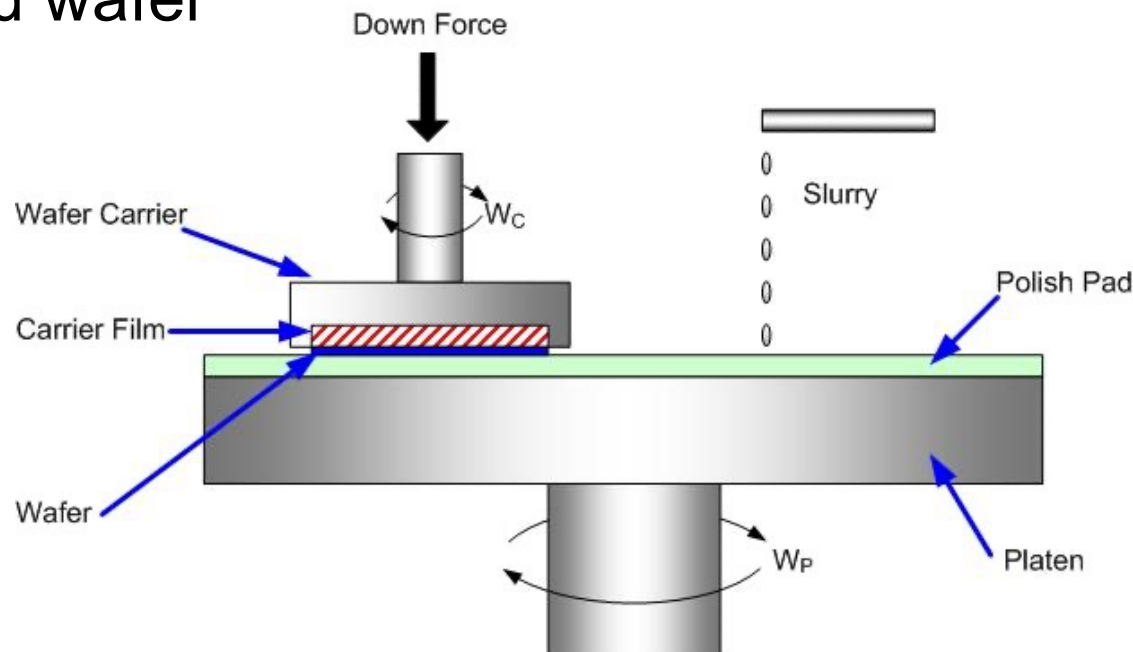
Dummy Fill Insertion

Outline

- Chemical-Mechanical Polishing (CMP)
- Filling Problem in fixed-dissection regime
- LP and Monte-Carlo (MC) approaches
- MC approach with Min-Fill objective
- Iterated MC method
- Computational experience
- Summary

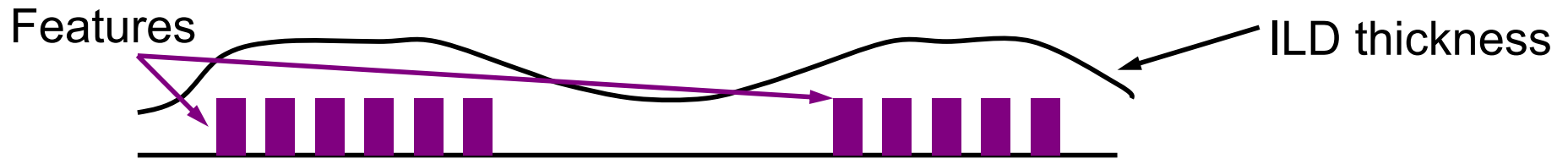
Chemical Mechanical Polishing

- For wafer surface planarization before adding next level of features
- Chemical Mechanical Polishing (CMP)
 - Chemically: abrasive slurry dissolves the wafer layer
 - Mechanically: a dynamic polishing head presses pad and wafer

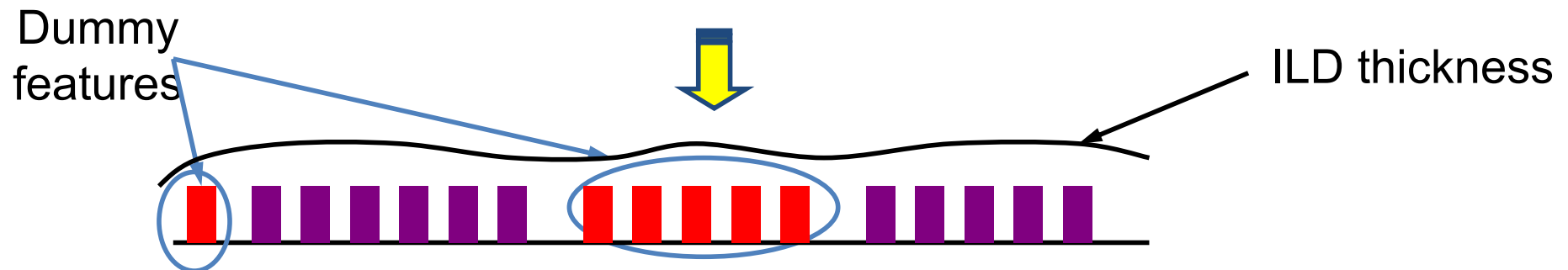


Source:
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CMP and Interlevel Dielectric Thickness



- Post CMP interlevel-dielectric (ILD) thickness is proportional to feature density
- Uneven features cause polishing pad to deform
- May insert dummy features to reduce variation



Objectives of Density Control

- Want to
 - minimize density variation to optimize post-CMP topography
 - minimize amount of fill to minimize impact on circuit performance
- Difficult to optimize both objectives simultaneously, so minimize one while keeping the other in check
- Objective for **Manufacturability** (i.e., **Min-Var**)
minimize window density variation
subject to upper bound on window density
- Objective for **Design Performance** (i.e., **Min-Fill**)
minimize total amount of added fill features
subject to upper bound on window density variation

Filling Problem

- **Given**

- ⊙ rule-correct layout in $n \times n$ region
- ⊙ window size = $w \times w$
- ⊙ window density upper bound U

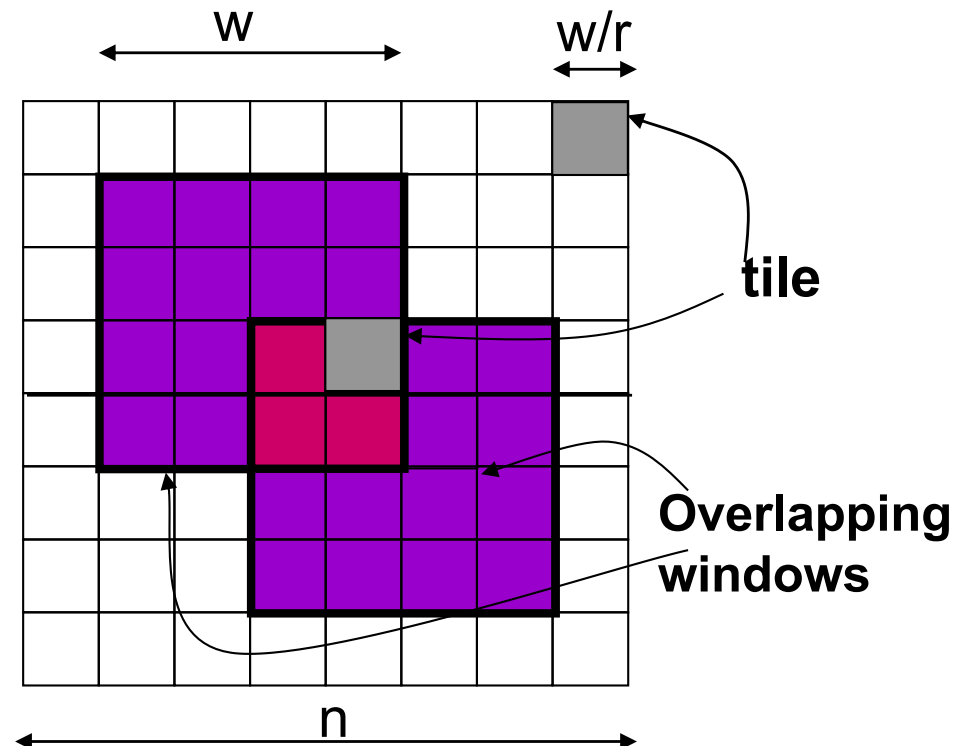
- **Fill layout with Min-Var or Min-Fill objective**

such that **no** fill is added

- ⊙ within buffer distance B of any layout feature
- ⊙ into any overfilled window that has density $\geq U$

Fixed-Dissection Regime

- Monitor only a **fixed** set of $w \times w$ windows
 - “offset” = w/r (example shown: $w = 4$, $r = 4$)
- Partition $n \times n$ layout with $nr/w \times nr/w$ fixed dissections
- Each $w \times w$ window is partitioned into r^2 tiles



Layout Density Models

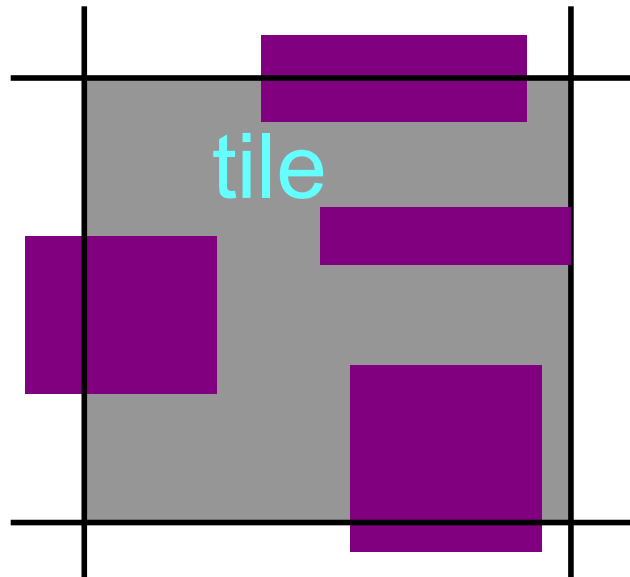
- **Spatial Density Model**

window density \approx sum of tiles' feature area

- **Effective Density Model (more accurate)**

window density \approx **weighted** sum of tiles's feature area

- elliptical weights decrease from window center to boundaries



Linear Programming Approach

- **Min-Var Objective**

[Kahng+ TCAD99]

- Maximize: M

- Subject to:

For any tile T

$$0 \leq p[T] \leq \text{slack}[T]$$

For any window W

$$\sum_{T \in W} (p[T] + \text{area}[T]) \leq U$$

$$M \leq \sum_{T \in W} (p[T] + \text{area}[T])$$

$p[T]$ = fill area of tile T

- spatial density model

- **Min-Fill Objective**

[Tian+ DAC00]

- ◉ Minimize:

$$\text{Fill amount} = \sum p[T]$$

- ◉ Subject to:

For any tile T

$$0 \leq p[T] \leq \text{slack}[T]$$

$$\text{LowerB} \leq \rho_0(T) \leq \text{UpperB}$$

$$\text{UpperB} - \text{LowerB} \leq \varepsilon$$

$\rho_0(T)$ = effective density for tile T

- ◉ effective density model

Monte-Carlo Approach with Min-Var Objective [Chen+ ASPDAC00]

- Fill layout randomly
 - Pick the tile for next filling geometry probabilistically
 - Higher priority of a tile \Rightarrow higher probability to be filled (i.e., Monte-Carlo)
 - Lock a tile if any containing window is overfilled
- Different schemes for setting tile priorities
 - *Slack* of the tile: will fill uniformly randomly
 - *U – max density of any window containing the tile:* tend to fill region as much as possible at the end
 - *U – min density of any window containing the tile:* will fill most underfilled window first (outperforms the other two schemes experimentally)

Monte-Carlo Approach with Min-Var Objective

- Different schemes for amount of fill geometry added per iteration
 - Insert a single filling geometry into a tile (better results)
 - Insert maximum possible filling geometries into a tile (faster)
- 2 possibilities for updating priorities after each iteration
 - Update priorities of all affected tiles (slightly better results)
 - Update priorities only of tiles which belong to any newly locked window (faster)

Monte Carlo-based Filling Algorithm

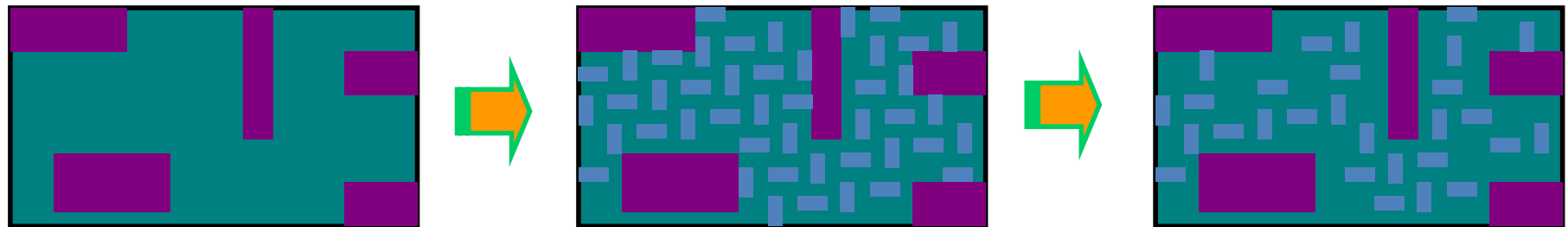
1. **For** each tile T initialize
2. $insert_in(T) = 0$
3. $priority(T) = f(U, slack(T), MaxWin(T))$
4. **While** the sum of tile priorities is positive **Do**
5. Select a random tile T according to priorities
6. $insert_in(T) = insert_in(T) + 1$; $slack(T) = slack(T) - unit_fill$
7. **If** $slack(T) < unit_fill$ **Then** $priority(T) = 0$
8. **Else** $priority(T) = priority(T) - unit_fill$
9. **For** each window W containing T **Do**
10. $area(W) = area(W) + unit_fill$
11. **For** each tile $T' \in W$ **Do**
12. Update $priority(T')$ according to $area(W)$
13. **For** each tile T **Do**
14. Randomly perturb sequence of grid positions: $random(i) = 1, \dots, slack(T)/unit_fill$
15. **For** $i = 1, \dots, insert_in(T)$ **Do**
16. Insert a unit-fill geometry into the $random(i)^{th}$ grid position
17. **Output** the filled layout

LP vs. Monte-Carlo

- LP
 - large runtime for large layouts
 - r -dissection solution may be suboptimal for $2r$ dissections
 - essential rounding error for small tiles
- Monte-Carlo
 - very efficient: $O((nr/w)\log(nr/w))$ time
 - scalability: handle large values of r
 - accuracy: reasonably high comparing with LP
 - drawback: excessive amount of fill features for Min-Var
- Remark: If we always choose the tile with the highest priority for filling instead, we get a greedy algorithm instead of MC. MC performs better than greedy on average.

Monte-Carlo Approach with Min-Fill Objective [Chen+ DAC00]

- Delete excessive fill
- Delete as much fill as possible while maintaining min window density $\geq L$



Monte-Carlo Approach with Min-Fill Objective

- Priority: *min density of any window containing the tile* – L

Min-Fill Monte-Carlo Algorithm

Input: $n \times n$ filled layout, fixed r -dissection, $w \times w$ window,
lower bound on window density L

Output: Filled layout with minimized amount of inserted fill area

While there exist an unlocked tile **do**

 Choose an unlocked tile T_{ij} randomly, according to its priority

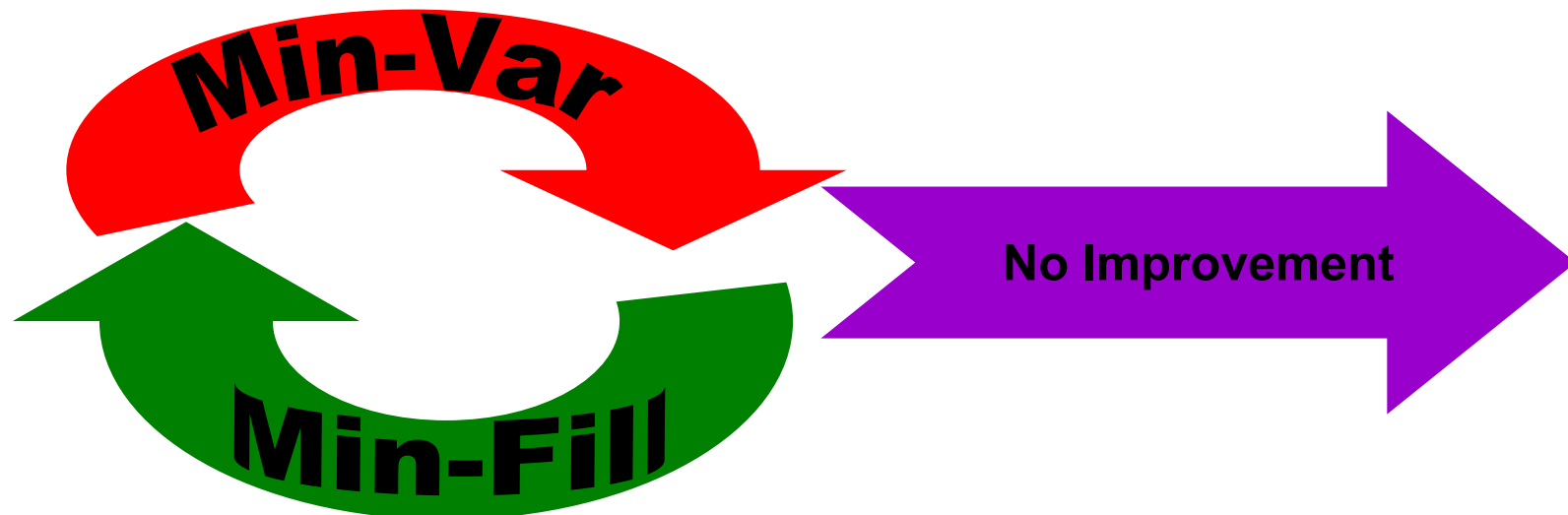
 Delete a filling geometry from T_{ij}

 Update priorities of tiles

Output resulting layout

Iterated Monte-Carlo Approach

- Repeat forever [Chen+ DAC00]
 - run **Min-Var** Monte-Carlo with maximum window density U
 - exit if no change in minimum window density
 - run **Min-Fill** Monte-Carlo Algorithm with minimum window density M



Computational Experience

- Testbed
 - GDSII input
 - hierarchical polygon database
 - C++ under Solaris
 - open-source code

- **Testcases**

Metal layers from industry standard-cell layouts

Test Case	L1	L2	L1x4	L2x4
layout size	125,000	112,000	250,000	224,000
#rectangles	49,506	76,423	198,024	305,692

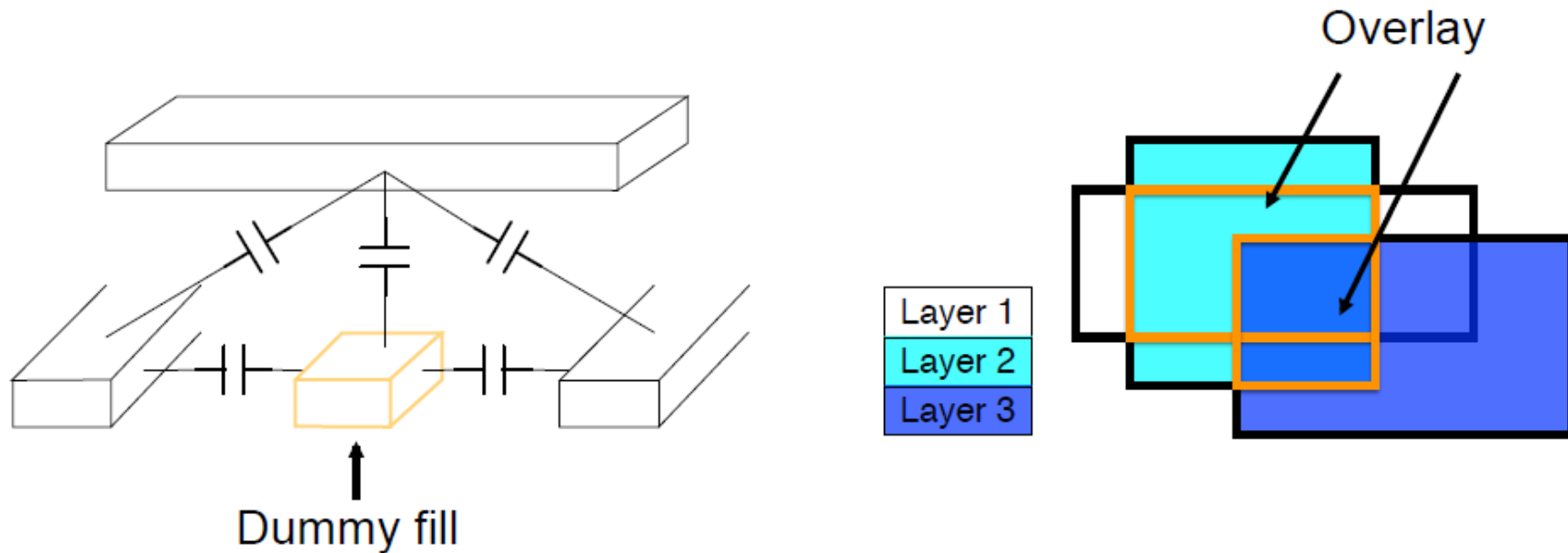
Computational Experience

	Orig Density		LP		MC		IMC	
Spatial Density Model								
Test case	Max	Min	Min	CPU	Min	CPU	Min	CPU
L1/32/8	0.21447	0.10414	0.19864	41.5	0.19221	17.3	0.19871	24.8
L2/32/8	0.22648	0.07039	0.14467	43	0.13565	24.4	0.14463	68.6
L1x4/32/8	0.21693	0.09657	0.18643	255.7	0.18282	72.3	0.18648	111.9
L2x4/32/8	0.22226	0.05776	0.14647	532.6	0.13824	117.7	0.14655	469.7
Effective Density Model								
L1/32/8	0.41625	0.16255	0.3197	32.4	0.31994	22.3	0.31994	23.9
L2/32/8	0.53585	0.07249	0.34777	66.8	0.31153	38.3	0.33858	68.9
L1x4/32/8	0.4327	0.14665	0.28487	171.5	0.28505	90.7	0.28505	100.9
L2x4/32/8	0.52179	0.04467	0.34176	637.4	0.30799	165.6	0.33524	435.9

- Iterated Monte-Carlo (IMC) approach is more accurate than standard MC approach and faster than LP approach

Extension

- Multi-layer
 - minimize overlay between adjacent layers to reduce coupling capacitance



References

- [Kahng+ TCAD99] Filling Algorithms and Analyses for Layout Density Control
- [Tian+ DAC00] Model-Based Dummy Feature Placement for Oxide Chemical-Mechanical Polishing Manufacturability
- [Chen+ ASPDAC00] Monte-Carlo Algorithms for Layout Density Control
- [Chen+ DAC00] Practical Iterated Fill Synthesis for CMP
- [Lin+ DAC15] High Performance Dummy Fill Insertion with Coupling and Uniformity Constraints